

Reference 6: Japanese Patent Application Laid Open No. H10-116886

Title of the Invention: Method for Holding Sample and Aligner

Filing Date: October 11, 1996

Applicant: Nikon Corporation

Extract:

See from line 5 in the 25th column to line 10 in the 31st column and
Figs. 33 to 48 in US Patent No. 6888621.

PATENT ABSTRACTS OF JAPAN

(11)Publication number : 10-116886

(43)Date of publication of application : 06.05.1998

(51)Int.Cl.

H01L 21/68
G03F 7/20
H01L 21/027

(21)Application number : 08-289305

(71)Applicant : NIKON CORP

(22)Date of filing : 11.10.1996

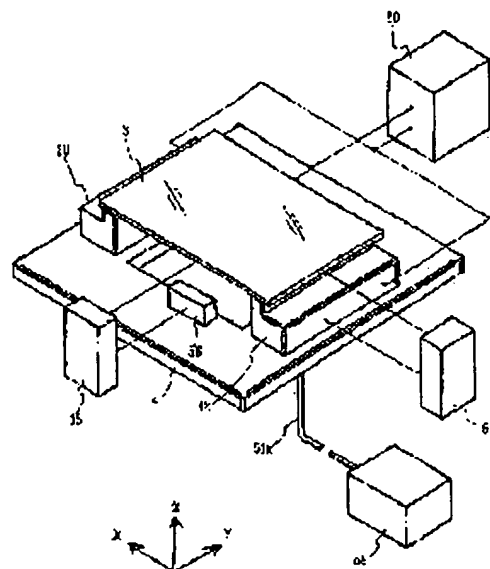
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(54) METHOD FOR HOLDING SAMPLE AND ALIGNER

(57)Abstract:

PROBLEM TO BE SOLVED: To optimally hold a sample on a flat plate against a sample table by sucking the sample by vacuum at the same time when it is sucked electrostatically to the sample table.

SOLUTION: When a reticle 3 is placed on reticle holders 30 and 32, a reticle stage control system controls a pressure control part 58 and a voltage control part 60, so that the reticle 3 is sucked to the holders 30 and 32 by vacuum and sucked thereto electrostatically at the same time. That is, a compressor in the pressure control part 58 sucks an air between the reticle 3 and the reticle holders 30 and 32 through suction holes of the reticle holders 30 and 32. In addition, the voltage control part 60 applies a specified voltage to a chrome layer and a dielectric layer so as to generate a static electricity therebetween, thereby allowing the reticle 3 to be sucked to the reticle holders 30 and 32 electrostatically. Thus, since the reticle 3 is held not only by vacuum suction but also by electrostatic suction, a holding force for the holders 30 and 32 can be increased.



LEGAL STATUS

[Date of request for examination] 07.10.2003

[Date of sending the examiner's decision of rejection] 22.08.2006

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]